FORM PTO-1449 INFORMATION DISCLOSURE CITATIONS IN AN APPLICATION

Atty Docket:	01-822	Serial #:
Applicant:	Sukharev, Catabay	
Filing Date:	2001.12.21	Group:

U.S. PATENT DOCUMENTS

Examiner	Cite #	Document Number	Date	Name	Class	Sub-Class	Filling Date
Initial							

FOREIGN PATENT DOCUMENTS

Examiner	Cite#	Document Number	Date	Country	Class	Sub-Class	Translation
Initial				•			

OTHER NON-PATENT DOCUMENTS

Exami	ner	Cite#	Author, title, date, pertinent pages, etc.
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A	Ø.	1	Wang et al., Stress-free polishing advances copper integrated with ultralow-k dielectrics, Solid State Technology,
			pp.101-106, October 2001.

Examiner

Date Considered:

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